## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.

10/696,432

Confirmation No. 6825

Applicant Filed

Ying-Lang Wang October 29, 2003

TC/A.U.

2813

Title

CMP Process Leaving No Residual Oxide Layer or Slurry

**Particles** 

Docket No.

N1085-90131 (TS01-167CB)

Customer No.

08933

Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

CERTIFICATE OF MAILING, 37 C.F.R. §1.8(a)

I certify that this correspondence and the enclosures mentioned therein are being deposited by First Class U.S. Mail with sufficient postage on the date shown below, addressed to Commissioner for Patents, PO Box 1450, Alexandna, Virginia

Richard A. Paikoff, Reg. No. 34

11:3/0

## **AMENDMENT AND RESPONSE**

Sir:

In response to the Office Action of December 28, 2004, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 4 of this paper.